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5/15/03
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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Antonio L. P. Rotondaro

Docket No: TI-31133

Serial No: 10/001,483 ✓

Conf. No: 1903

Examiner: Michelle Estrada

Art Unit: 2823

Filed: 11/01/2001 ✓

For: METHOD TO IMPROVE THE UNIFORMITY AND REDUCE THE SURFACE ROUGHNESS
OF THE SILICON DIELECTRIC INTERFACE

LETTER TO OFFICIAL DRAFTSPERSON

Commissioner For Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Attention: Official Draftsperson

MAILING CERTIFICATE UNDER 37 C.F.R. §1.8(a)

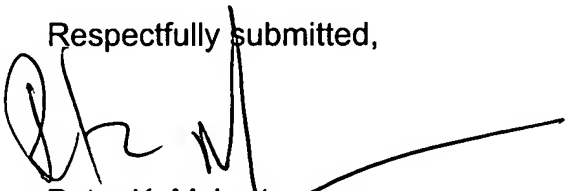
I hereby certify that the above correspondence is being deposited with the U.S. Postal Service with sufficient postage as First Class Mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450 on 5-9-03.


Ann Trent

Dear Sir:

Transmitted herewith for filing are four sheets of corrected formal drawings for the above identified application. Charge any necessary fees to the deposit account of Texas Instruments Incorporated, Account No. 20-0668.

Respectfully submitted,


Peter K. McLarty
Attorney for Applicant
Reg. No. 44,923

*approved
me
7/16/03*

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